

Japan TC Chapter of Automation Technology Global Technical Committee Meeting Summary and Minutes

Japan Standards Summer 2016 Meetings
Monday, June 27 2016, 1:30 p.m. – 16:30 p.m.
SEMI Japan office, Tokyo, Japan

Next Committee Meeting

15:45-18:00 Wednesday, July 27, 2016 <Japan Standard Time>
SEMI Japan, Tokyo, Japan

Committee Announcements (optional)

None

Table 1 Meeting Attendees

Italics indicates virtual participants

Co-Chairs: Makoto Ishikawa (Nisshinbo Mechatronics), Teruaki Ito (Mitsubishi Electric), Terry Asakawa (Tokyo Electron)

SEMI Staff: Junko Collins (SEMI Japan)

Attendee:6+ **SEMI:** 1

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Mitsubishi Electric	Ito	Teruaki	Tokyo Electron	Asakawa	Terry
SIEMENS	Ohbuchi	Fumiyasu	Mitsubishi Electric	Yutani	Takashi
Tokyo Electron	Murata	Naoko	Mitsubishi Electric	Takahashi	Katsuyoshi
			SEMI Japan	Collins	Junko

Table 2 Leadership Changes

None

Table 3 Ballot Results

None

Table 4 Authorized Ballots

None

Table 5 Authorized Activities

None

Table 6 New Action Items (move to Section 9, Action Item Review)

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
2016-0627-01	T. Ito	To create mapping International Standards regarding Smart Manufacturing by July 4. Keyword: IEC, ISO, U4.0
2016-0627-02	Staff	1 To gain written approval to change designation letters regarding PV35, PV35.1 and PV55. 2 To ask and to get response from Regulation SC conflict between A5-1.1 and A5-1.2 in Appendix 5 before the next TC Chapter meeting. Will be report at the next meeting.
2016-0627-03	EIS TF	1 To work on AI 2016-0119-02 after PV35.1 is changed to Ax.x 2 To address other items to be revised at the same time

Table 7 Open Actions Items (move to Section 9, Action item Review)

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
2016-0119-02	EIS TF	To submit the SNARF for revision to PV35.1 to remove limitation data block length to the TC Chapter before the next TC Chapter Meeting. <i>Open</i>
2016-0422-01	Chairs and Staff	To prepare SNARF for changing designation <i>Open</i>
2016-0422-02	EIS Task Force (T. Yutani)	To prepare SNARF for MD Specification <i>Open</i>

1 Welcome, Reminders, and Introductions

Teruaki Ito (Mitsubishi Electric), co-chair, called the meeting to order at 13:30. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed by SEMI Staff. Attendees introduced themselves.

Attachment:

2 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting.

Motion:	To approve the previous meeting minutes written as it is.
By / 2nd:	Naoko Murata (Tokyo Electron) / Fumiyasu Ohbuchi (SIEMES)
Discussion:	None
Vote:	5 in favor and 0 opposed. Motion Passed.

Attachment:

3 Liaison Reports

3.1 Europe TC Chapter

There is no special report.

3.2 FlowMaster Forum

3.2.1 T. Asakawa introduced SEMI Smart Manufacturing Advisory Council activity. This group discusses how SEMI steers their direction of smart manufacturing as an association having members who has knowhow of manufacturing especially factory automation. T. Asakawa and F. Ohbuchi are members of this council from Japan.

Attachment: No attachment

4 SEMI Staff Report

Junko Collins (SEMI Japan) gave the SEMI Staff Report as attached materials. Of note:

- Global SEMI Events
- Global Standards Meetings Schedule
- Ballot Critical Dates
- A&R Report
- Contact Information

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Attachment:

5 Ballot Review

None

6 Subcommittee & Task Force Reports

6.1 Equipment Interface Specification (EIS) Task Force

6.1.1 MDMD Specification was discussed at the task force meeting before this TC Chapter meeting in the morning.

6.1.2 T. Yutani will step down from the task force leader position and the task Force leader will be switched to K. Takahashi. This will be discussed at the next task force meeting and will be officially reported at the next TC Chapter meeting.

7 Old Business

7.1 TC Chapter Project

7.1.1 Three-year Project Period

- There is no active SNARF approved by Japan TC Chapter.

Attachment: none

7.1.2 5-year Review

- Members reviewed the list. No action was needed at this meeting.

Attachment: none

8 New Business

8.1 New SNARF

8.1.1 SNARF for changing designation letters of PV35, PV35.1 and PV55

8.1.1.1 SNARF for changing designation letters of PV35 and PV 35.1 was reviewed.

8.1.1.1.1 TC Chapter has to get written approval to change the designation letters from SEMI HQ before submitting the SNARF. Staff, Junko Collins will ask SEMI HQ its approval of designation letter change.

8.1.1.1.2 Staff was requested to ask Regulation SC about conflict between A5-1.1 and A5-1.2 PG Appendix 5, February 12, 2016 and report it at the next TC Chapter. SNARFs will also be reviewed again at the next TC Chapter meeting.

8.1.2 SNARF approval for “Revision to add a New Subordinate Standard for Specification for Material Data Definition for PV35 Horizontal Communication”

8.1.2.1 SNARF was not ready yet. Task Force needs more discussion to brush up the draft of the SNARF and communication with other region.

9 Action Item Review

9.1 Open Action Items

Junko Collins (SEMI Japan) reviewed the open action item. This can be found in the Open Action Items table at the beginning of these minutes.

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2016-0422-01	Chairs and Staff	To prepare SNARF for changing designation Open
2016-0422-02	EIS Task Force (T. Yutani)	To prepare SNARF for MD Specification Open

9.2 New Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
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10 Next Meeting and Adjournment

The next meeting of the Japan TC Chapter of Automation Technology Global Technical Committee is scheduled for 3:45 p.m. – 6:00 p.m., Wednesday, July 27, 2016, SEMI Japan office in Tokyo.

Respectfully submitted by:
Junko Collins
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SEMI Japan
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Email: jcollins@semi.org

Minutes approved by: the meeting on July 27

<Makoto Ishikawa> (Nisshinbo Mechatronics), Co-chair	
<Terry Asakawa> (Tokyo Electron), Co-chair	
<Teruaki Ito>(Mitsubishi Electric), Co-chair	